



<b>INFORMATION DISCLOSURE CITATION PTO-1449</b>	Atty. Docket No. 000593B	Serial No. 10/615,381
	Applicant(s): NISHIUCHI, et al.	
	Filing Date: July 9, 2003	Group Art Unit: 1763

### U.S. PATENT DOCUMENTS

Examiner Initial		Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
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_____	AB	4,534,840	Shindo et al.	08-13-1985	204	192	
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### FOREIGN PATENT DOCUMENTS

		Document No.	Date	Country	Translation (Yes or No)
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_____	AG	EP 0 811 994	12-10-1997	EPO	
_____	AH				
_____	AI				
_____	AJ				

Examiner	Date Considered
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IDS not considered  
- Richard Buhl



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- Richard B. B. B.